ABSTRACT OF THE DISCLOSURE

HIGH FREQUENCY COUPLER, AND PLASMA PROCESSING APPARATUS AND METHOD

A high frequency coupler wherein a section of the high frequency coupler cut by a plane perpendicular to a straight line which connects the center of a joint surface between the coupler and an output portion of a matching circuit and the center of a joint surface between the coupler and the antenna has a configuration such that the section contains a plurality of line segments arranged radially from a point adjacent the center of the section. This arrangement enables the flow of currents having good symmetry, uniform distribution of currents flowing on antenna, and uniform plasma generation.

Figure 2.